

5 obliquely held by the device at a predetermined position within a chamber of said apparatus, said device comprising:

a substrate holder for supporting the back surface of said wafer thereon,

10 a rotating means for circumferentially rotating said wafer along with the substrate holder, and

a plurality of holding members provided on said substrate holder and [adapted to] placed in contact with [a] the peripheral edge of said wafer loaded [on said substrate holder] thereon, said holding members [exerting a holding force of] being adapted  
15 to act against said peripheral edge of said wafer to exert a holding force toward the center of said wafer in such degree that said wafer is prevented from coming off when said wafer is rotated along said substrate holder by said rotating means.

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